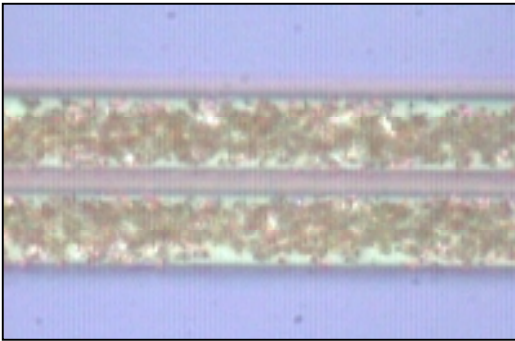


Effect of Chamber Cleaning on Grass Formation during Silicon Etching in P5000

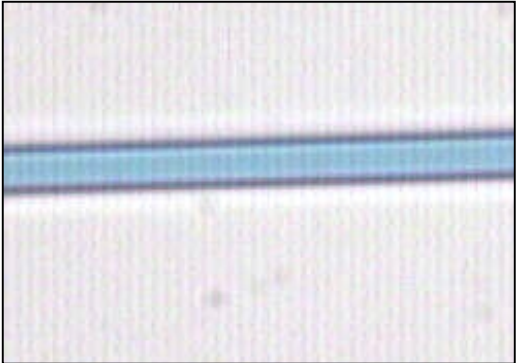
Before chamber wet clean

After chamber wet clean

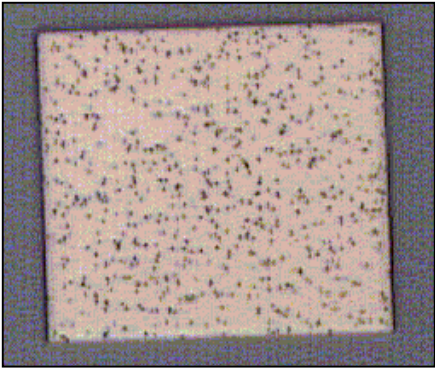
Top view of "Si grass" on device



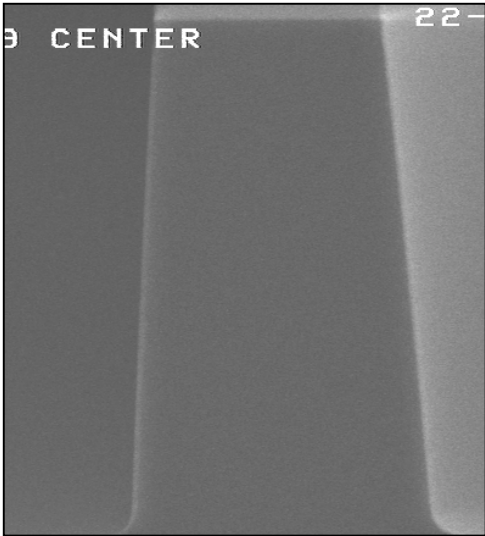
No grass



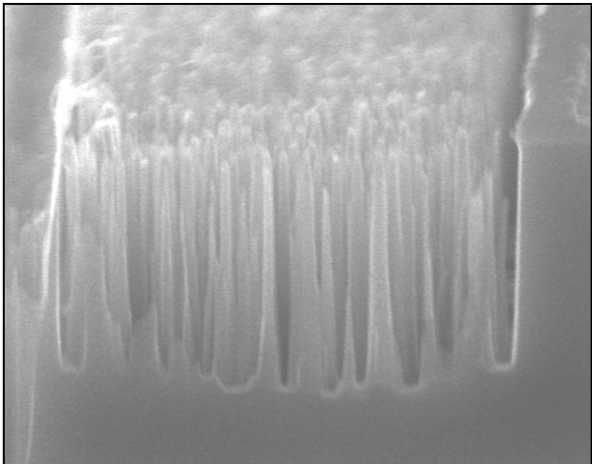
Top view of "Si grass" on device



No grass



Cross-section SEM picture of grass



From Song Pang July 2001